

Samenvatting Microfluidic jet systems

Publicaties:

J. Wei, M. van der Velden, P.M. Sarro, Fabrication of vertical electrodes on channel sidewall for picoliter liquid measurement, Transducers'07 (EurosensorsXXI), Lyon, 10-14 Jun, 2007.

M. van der Velden, J.W. Spronck, R.H. Munnig Schmidt, Capacitive sensor integrated in silicon cavity for microfluidic jet systems, Euspen conference, Bremen, 20-24 May, 2007.

M. van der Velden, J. Wei, J.W. Spronck, R.H. Munnig Schmidt, P.M. Sarro, Characterization of a nozzle-integrated capacitive sensor for microfluidic jet systems, IEEE sensors, October 2007

J. Wei, T. Chu Duc, M. van der Velden and P. M. Sarro, Tuning of DRIE process for Capacitive Sensor in Inkjet Nozzle, SAFE 2007, Veldhoven, Netherlands, pp. 625-628, Nov. 2007

T. M. Verhaar, J. Wei and P. M. Sarro, Pattern transfer on a vertical cavity sidewall using SU8, J. Micromech. Microeng. 19 (2009) 074018

T. M. Verhaar, J. Wei and P. M. Sarro, Highly uniform coating of vertical sidewall for 3D pattern definition, 19th MicroMechanics Europe, Sept. 2008, Aachen, Germany.

J. Wei, C. Yue, Z. L. Chen, Z. W. Liu, K. A. A. Makinwa, P. M. Sarro, Implementation and Characterization of a femto-Farad Capacitive Sensor for pico-Liter Liquid Monitoring, Eurosensors XXIII, Sept. 2009, Lausanne, Switzerland. (to be published)

C. Yue, J. Wei, Z. L. Chen, Z. W. Liu, P. M. Sarro, Characterization of Femto-Farad-Level Capacitive MEMS Sensors using Lock-in Architecture, Sept. 2009, Toulouse, France. (to be published)

Contactpersoon:

TU Delft
DIMES
Lina Sarro
p.m.sarro@tudelft.nl
015-278 77 08